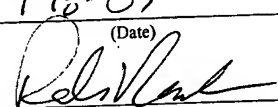




PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Pomarede, et al.	)	Group Art Unit: Unknown
App. No.	:	10/626,212	)	
Filed	:	July 24, 2003	)	
For	:	SURFACE PREPARATION PRIOR TO DEPOSITION	)	
Examiner	:	Unknown	)	

I hereby certify that this correspondence and all marked attachments are being deposited with the United States Postal Service as first-class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on 9-18-03 (Date)  
  
Rabinder N. Narula, Reg. No. 53,371

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing twenty five (25) references that have been previously submitted by the Applicant and/or Examiner in a related Application (Serial Number 09/944,734 filed August 31, 2001) and additional copies are therefore not enclosed herewith in accordance with the provisions of 37 C.F.R. 1.98(d). This Information Disclosure Statement is being filed before the receipt of a first Office Action on the merits, and presumably no fee is required in accordance with 37 C.F.R. § 1.97(b)(3). If a first Office Action on the merits was mailed before the mailing date of this Statement, the Commissioner is authorized to charge the fee set forth in 37 C.F.R. § 1.17(p) to Deposit Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

By: 

Rabinder N. Narula  
Registration No. 53,371  
Attorney of Record  
Customer No. 20,995  
(949) 760-0404



FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. ASMEX.284C1	APPLICATION NO. 10/626,212
INFORMATION DISCLOSURE STATEMENT BY APPLICANT  (USE SEVERAL SHEETS IF NECESSARY)		APPLICANT Pomarede, et al.	
		FILING DATE July 24, 2003	GROUP Unknown

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	1	2,394,930	2/12/46	McRae			
	2	3,895,127	7/15/75	Comizzoli			
	3	4,056,642	11/1/77	Saxena et al.			
	4	4,292,343	9/29/81	Plaettner et al.			
	5	4,343,830	8/10/82	Sarma et al.			
	6	4,436,761	3/13/84	Hayashi et al.			
	7	4,544,571	10/1/85	Miller			
	8	4,645,683	2/24/87	Gourrier et al.			
	9	4,766,006	8/23/88	Gaczi			
	10	5,135,775	8/4/92	Foller et al.			
	11	5,281,546	01/25/94	Possin et al.			
	12	5,576,071	11/19/96	Sandhu			
	13	5,587,205	12/24/96	Saito et al.			
	14	5,780,115	7/14/98	Park et al.			
	15	5,939,763	08/17/99	Hao et al.			
	16	5,950,107	09/07/99	Huff et al.			
	17	5,990,013	11/23/99	Berenguer et al.			
	18	5,993,916	11/30/99	Zhao et al.			
	19	6,107,192	08/22/00	Subrahmanyam et al.			
	20	6,200,866	03/13/01	Ma et al.			

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	21	JP 60 254621 A	16.12.85	Patent Abstracts of Japan				
	22	JP 2000 160342 A	13.10.00	Patent Abstracts of Japan				
	23	0 617 461 A2	03/16/94	EPO				

EXAMINER

DATE CONSIDERED

\*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.

SEP 22 2003  
PATENT & TRADEMARK  
JC109

FORM PTO-1449 U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT BY APPLICANT  (USE SEVERAL SHEETS IF NECESSARY)	ATTY. DOCKET NO. ASMEX.284C1	APPLICATION NO. 10/626,212
	APPLICANT Pomarede, et al.	
	FILING DATE July 24, 2003	GROUP Unknown

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
	24	Kim, H. and R. Reif, <i>Thin Solid Films</i> , Vol. 289:192-198 (1996), "In-situ low-temperature (600°C) wafer surface cleaning by electron cyclotron resonance hydrogen plasma ...."
	25	Ramm J. and E. Beck, <i>Thin Solid Films</i> , Vol. 246:158-163 (1994), "Low temperature epitaxial growth by molecular beam epitaxy on hydrogen-plasma-cleaned silicon wafers."

H:\DOCS\KFS\KFS-2698.DOC  
091803

EXAMINER	DATE CONSIDERED
*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	